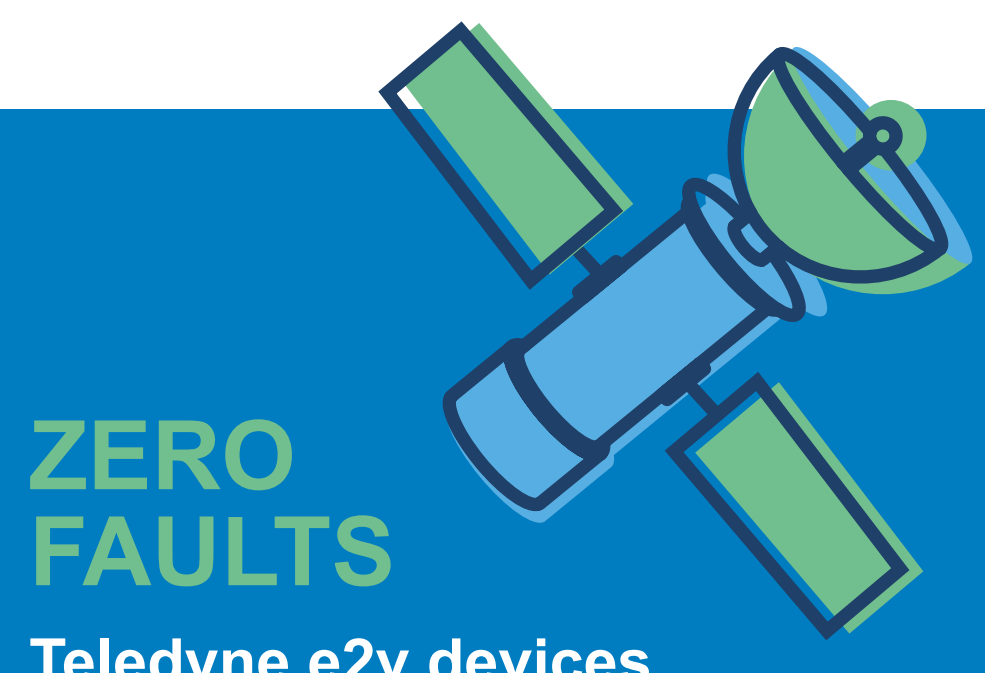


# Teledyne e2v Space Flows Comparison Chart

Overview and comparison chart of globally recognised and Teledyne e2v's own space flows, including military, industrial and commercial flows, to help our customers find the most suitable quality grade. Read more about our products by flashing the following QR Code:



**WE DELIVER**  
Over 6,000 space grade ADC, DAC and Processor flight models and over 40,000 avionics flight models delivered.



**ZERO FAULTS**  
Teledyne e2v devices have never failed in-orbit since delivering the first space grade flight parts over 25 years ago.



**GLOBAL STANDARDS**  
Our Semiconductor manufacturing site has been awarded the highest quality certifications, including EN9100 and QML Q. V and Y.

**CLASSIFICATIONS**

MIL-PRF-38535 Class Q: US DLA for hermetically sealed parts for military applications (class level B)

MIL-PRF-38535 class V: US DLA for hermetically sealed parts for space applications (class level S)

MIL-PRF-38535 Class Y: US DLA standard for non hermetic parts for Space applications (class level S)

ESCC9000: European standard for hermetic and non hermetic parts for space applications (class level S)

PEM-INST-001: US NASA guidelines for Plastic Encapsulated Microcircuits (PEM) for space applications (Level 1 to 3)

ECSS-Q-ST-60-13: European standard for commercial electronic parts for space applications (Grade 1 to 3)

JESD47: JEDEC standard for commercial parts. Operating temperature range of parts from Commercial Grade to Military Grade.

**KEY TERMS**

C-SAM: Confocal – Scanning Acoustic Microscopy

PIND: Particle Impact Noise Detection

DPA: Destructive Physical Analysis

HTOL: High Temperature Operating Life

PDA: Percentage Defect Allowed

QCI: Quality Performance Inspection

LVT: Lot Validation Testing

LAT: Lot Acceptance Test

SMD: Standard Microcircuit Drawing

EM: Engineering Model

EQM: Engineering Qualification Model

FM: Flight Model

-X1: Teledyne X1

Please refer to definition NE 89S 240869

## FLOW CHARTS

Main Process Flow Steps	Method / Condition	CERAMIC															ORGANIC										Telodyne X1									
		HERMETIC					NON-HERMETIC					NON-HERMETIC					NON-HERMETIC																			
		JESD47	EQM Manufactured Internally		QML-Q	QML-V		NB1	QML-Y		"-Nx" NASA level			"-Ex" ECSS Class			EQM Manufactured Internally		JESD47																	
C, V, F, M	(wired)	(Flip Chip)	(wired)	(wired)	(Flip Chip)	(wired)	(Flip Chip)	(Flip Chip)	Level 1	Level 2	Level 3	Level 1	Level 2	Level 3	(wired)	(Flip Chip)	C, V, F, M																			
Specification reference	INTERNAL PROCEDURE					MIL-PRF-38535					ESCC 9000	MIL-PRF-38535		EEE-INST-002 / PEM-INST-001			ECSS-Q-ST-40 / ECSS-Q-ST-60-13			INTERNAL PROCEDURE		INTERNAL PROCEDURE	INTERNAL PROCEDURE													
Wafer Lot Acceptance	MIL-STD-883 TM5007 / QM Plan	✓ If appl.	✓ If appl.	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓

## QUALITY REQUIREMENTS

Teledyne-e2v program benefits	ISO9001 or EN9100	EN9100	EN9100	EN9100	EN9100	EN9100	EN9100	EN9100	EN9100	EN9100	EN9100	EN9100	EN9100	EN9100	EN9100	EN9100	EN9100	EN9100	EN9100	EN9100	EN9100	EN9100	EN9100
Applied Quality Management System	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓
Single Fab, assembly and test sites	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓
Single wafer diffusion lot	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓